

FIG 1: PLASMA SPUTTER DEPOSITION SYSTEM

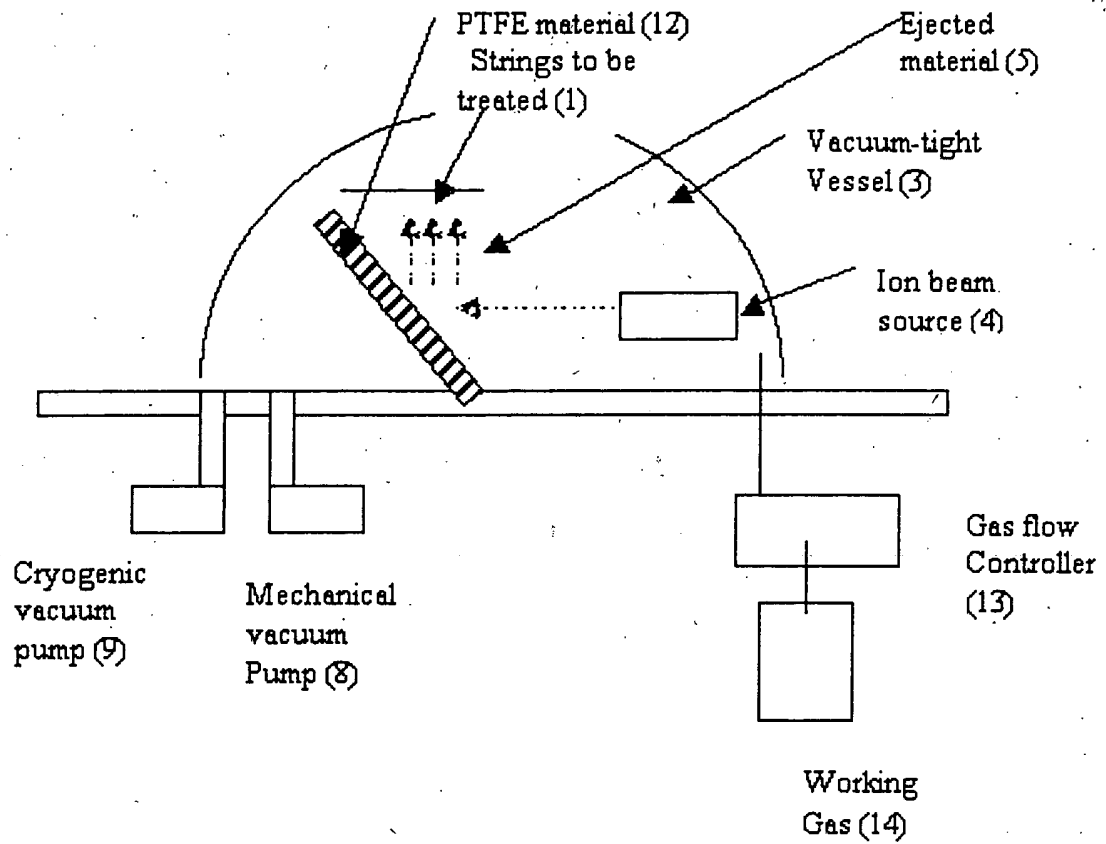


FIG 2: ION BEAM DEPOSITION SYSTEM

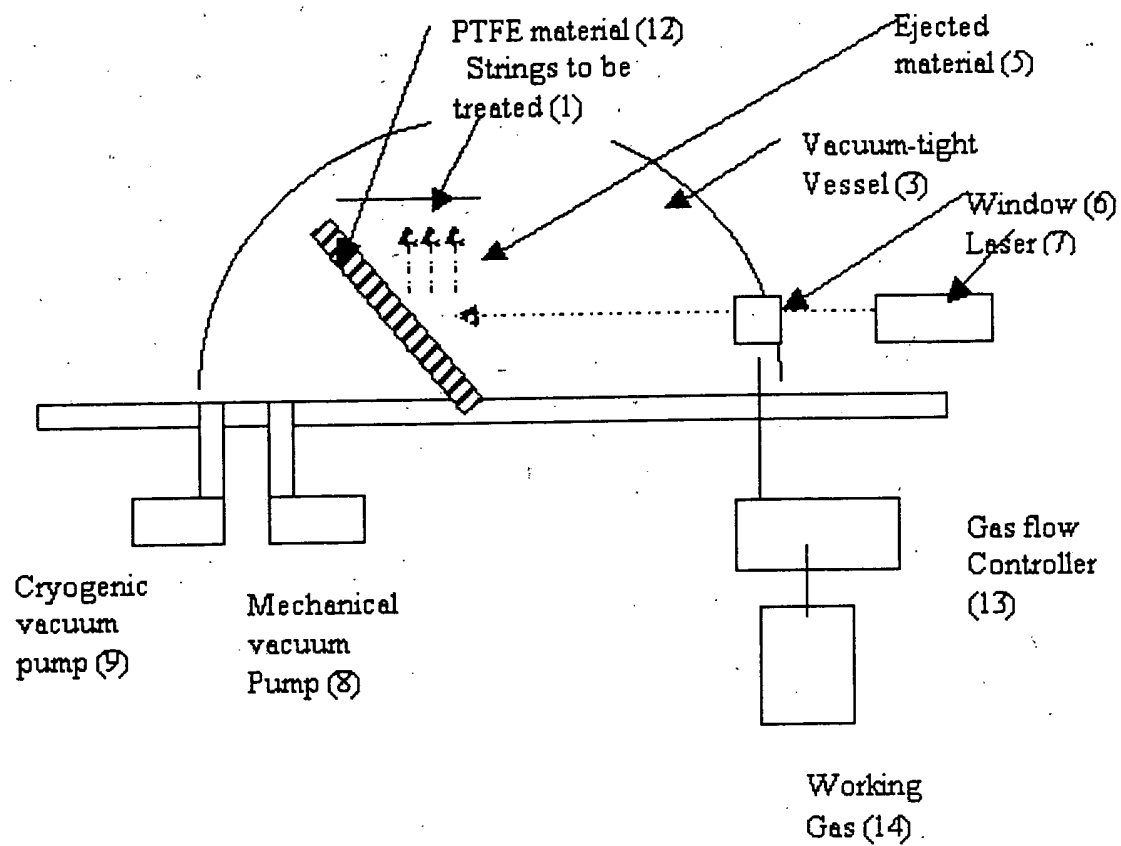


FIG 3: LASER DEPOSITION SYSTEM

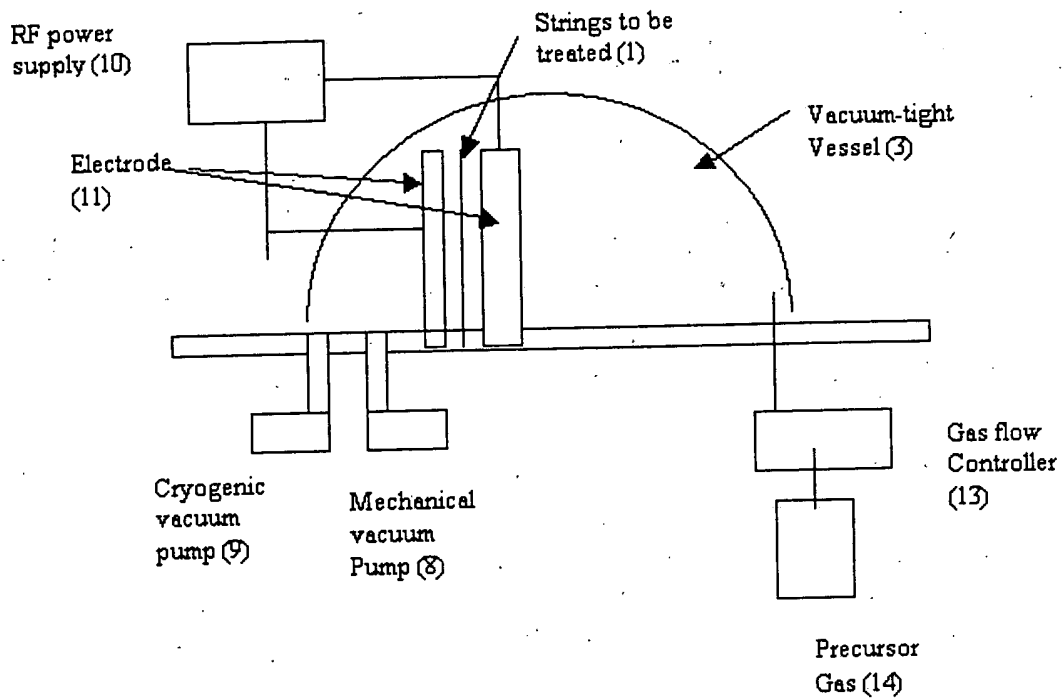


FIG 4: PLASMA CHEMICAL VAPOR DEPOSITION SYSTEM

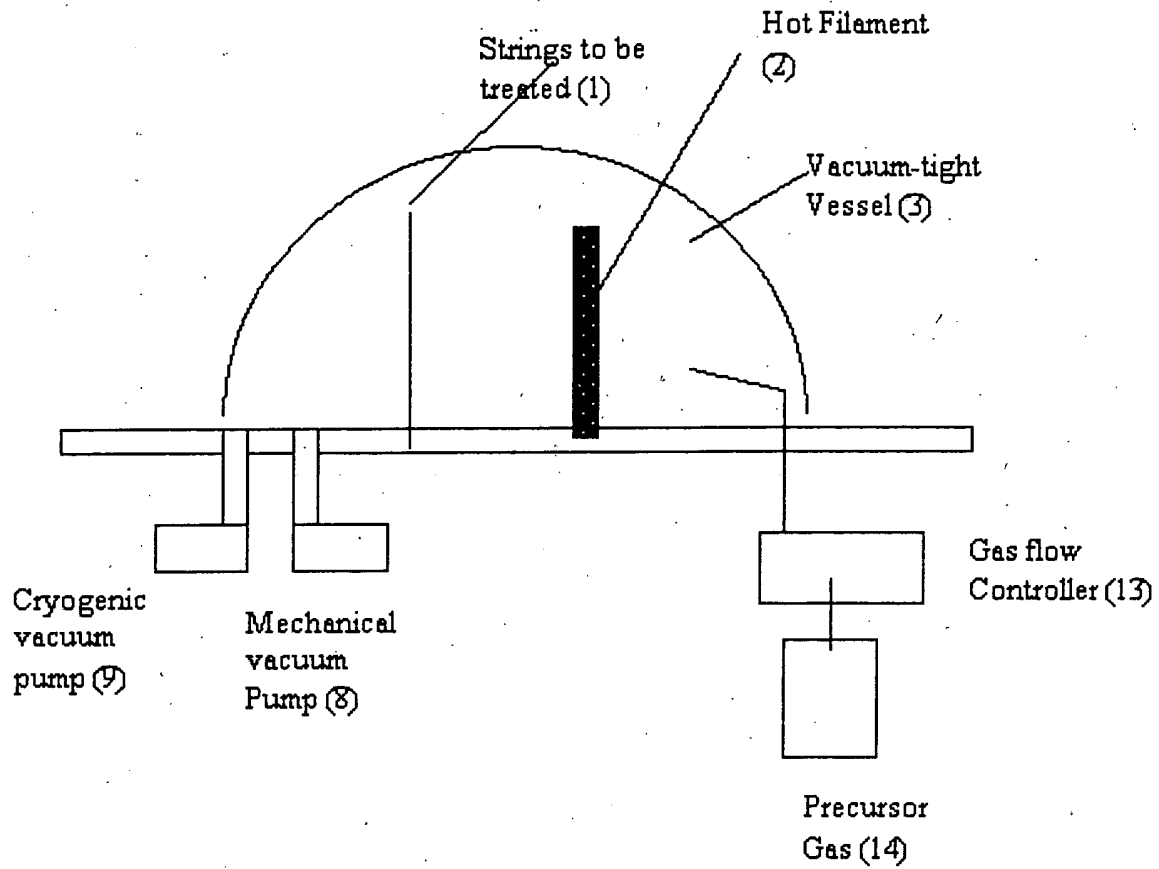


FIG 5: HOT FILAMENT CHEMICAL VAPOR DEPOSITION SYSTEM

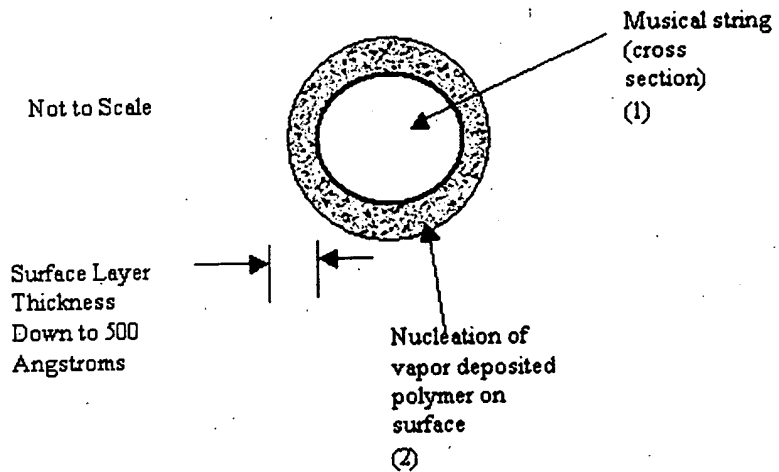


FIGURE 6: MUSICAL STRING TREATED
WITH VAPOR DEPOSITED POLYMER

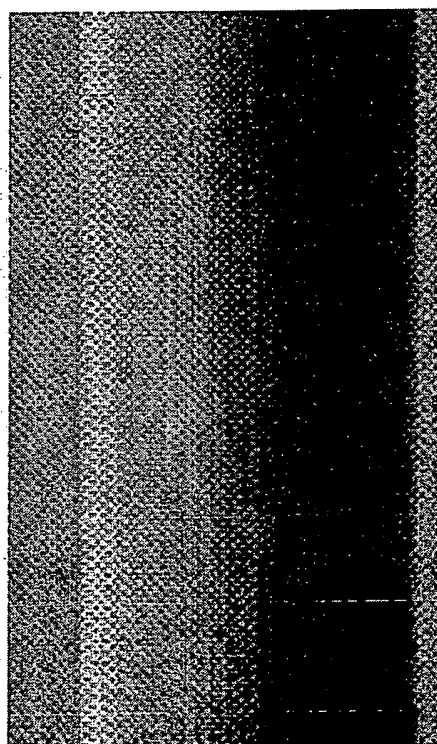
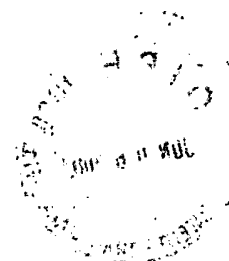


FIGURE 7

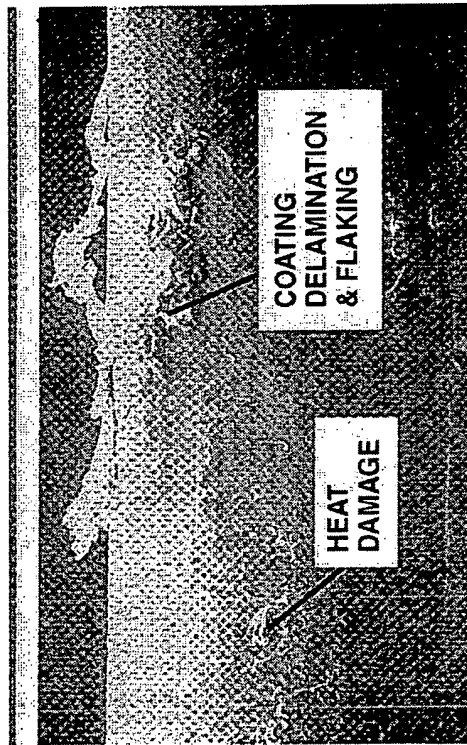
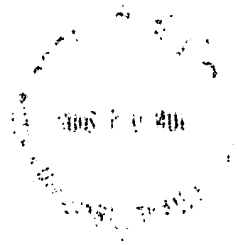


FIGURE 8

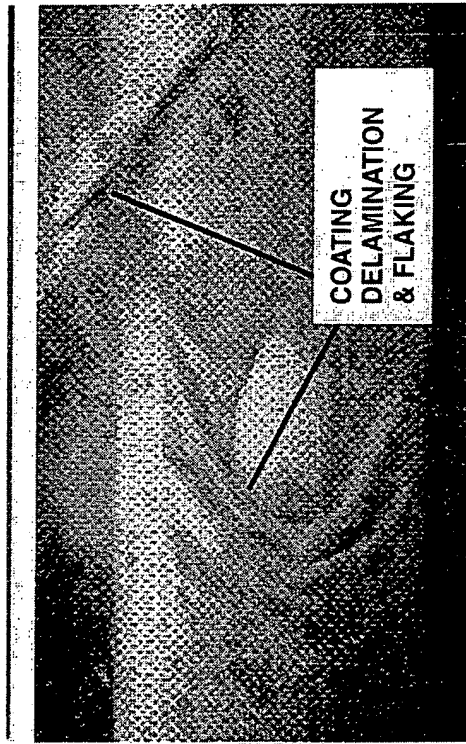
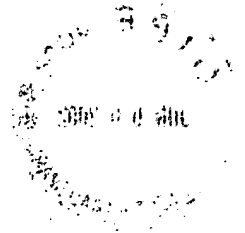
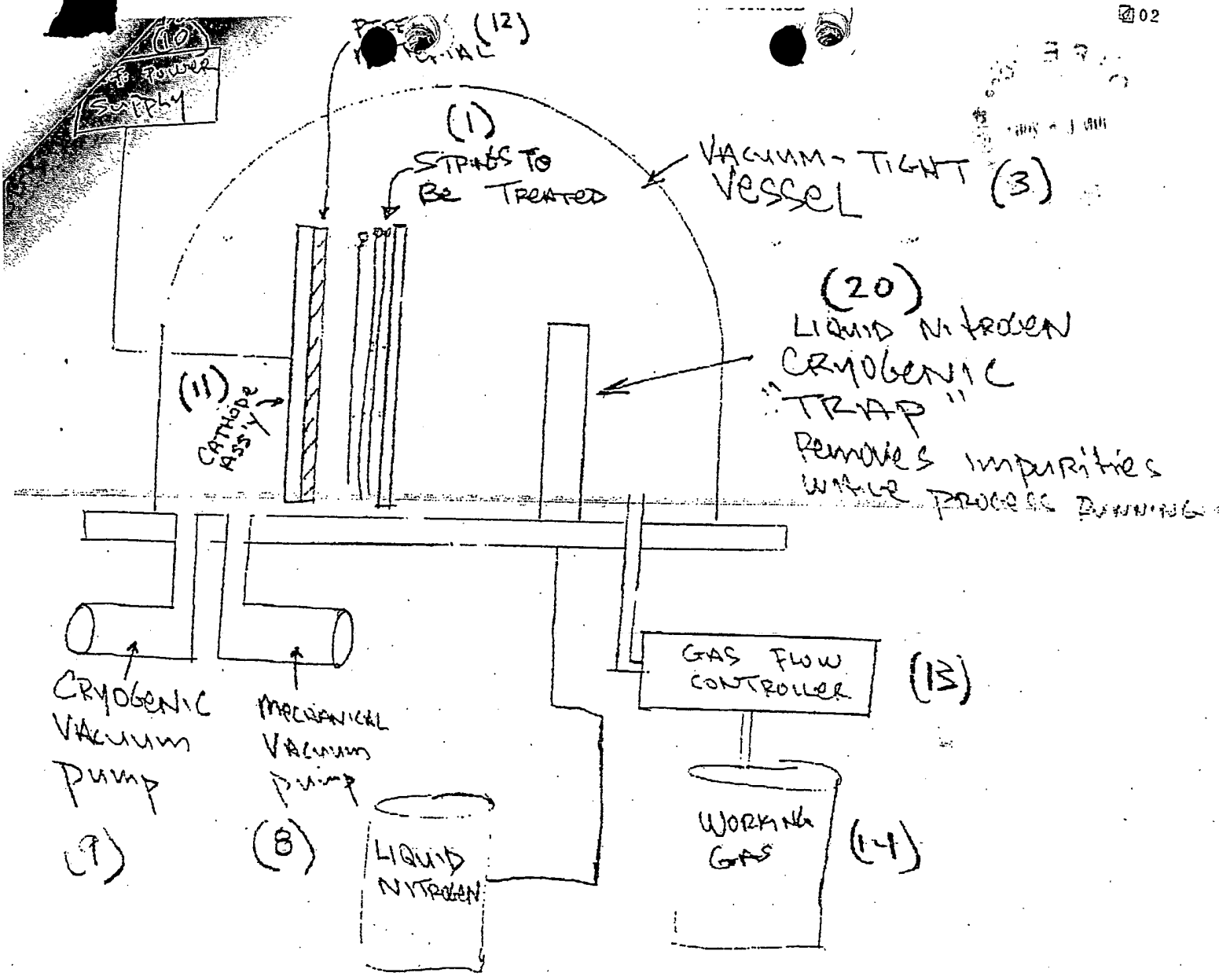
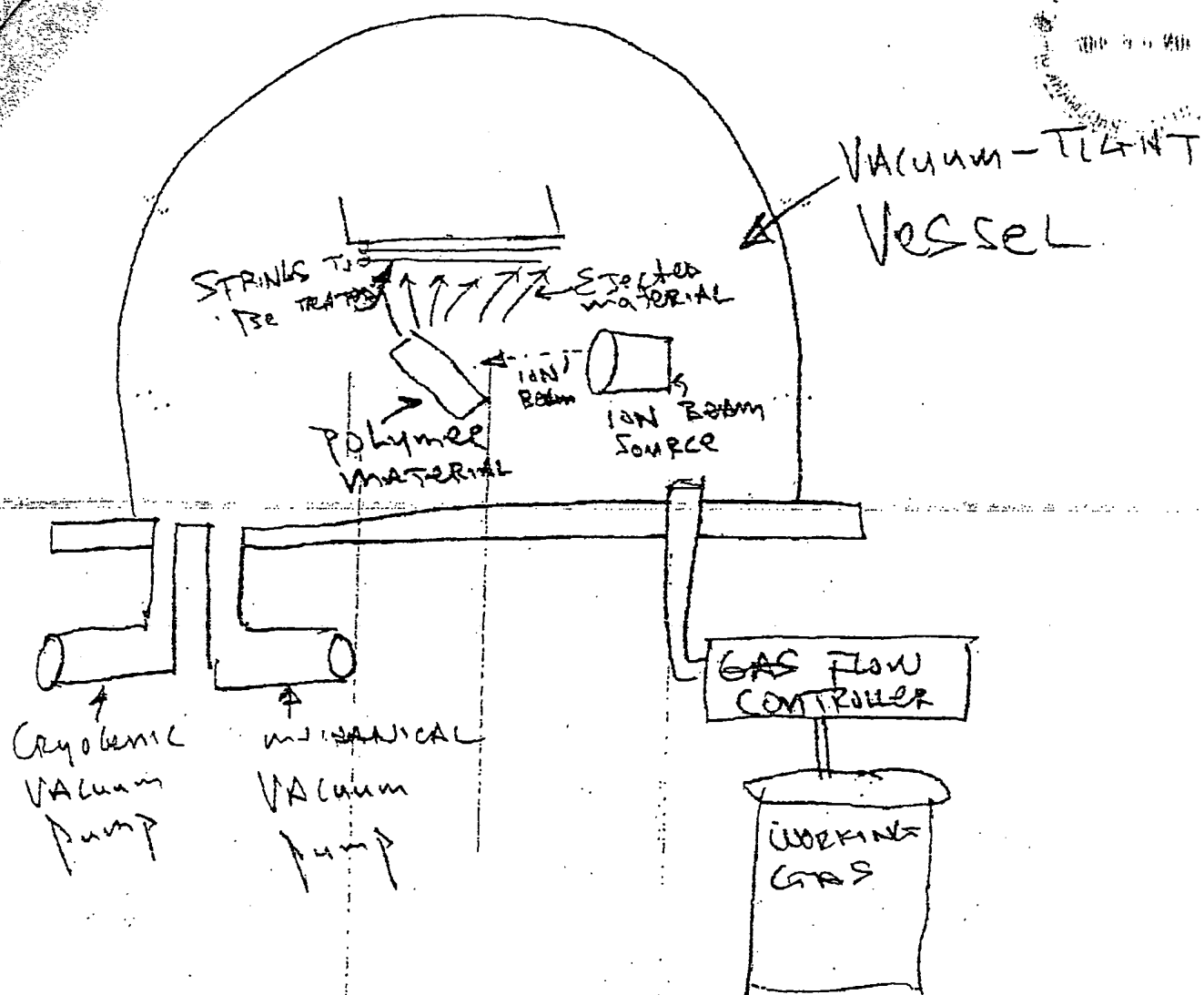


FIGURE 9



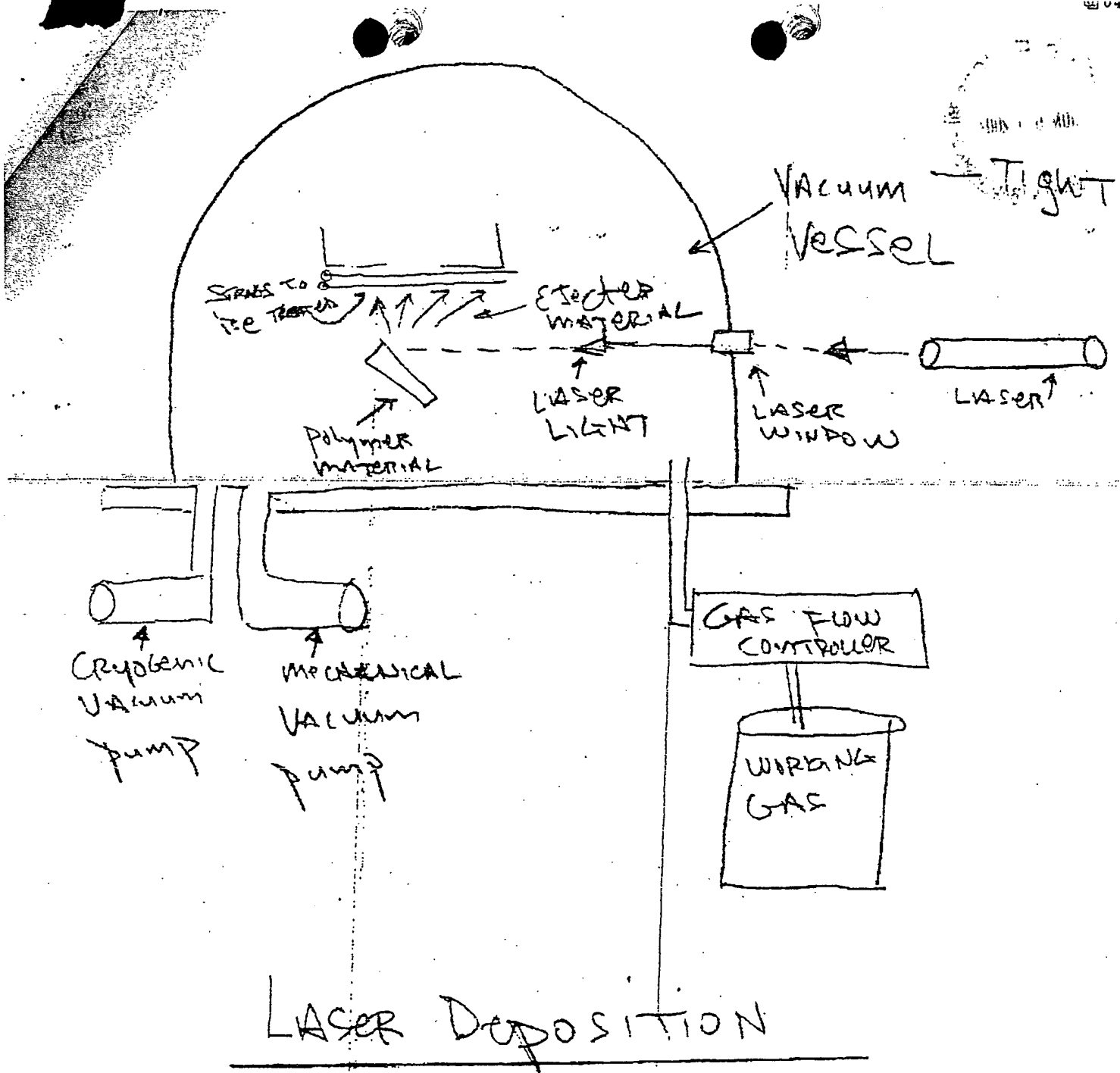
PLASMA SPUTTER DEPOSITION

Fig. 1.



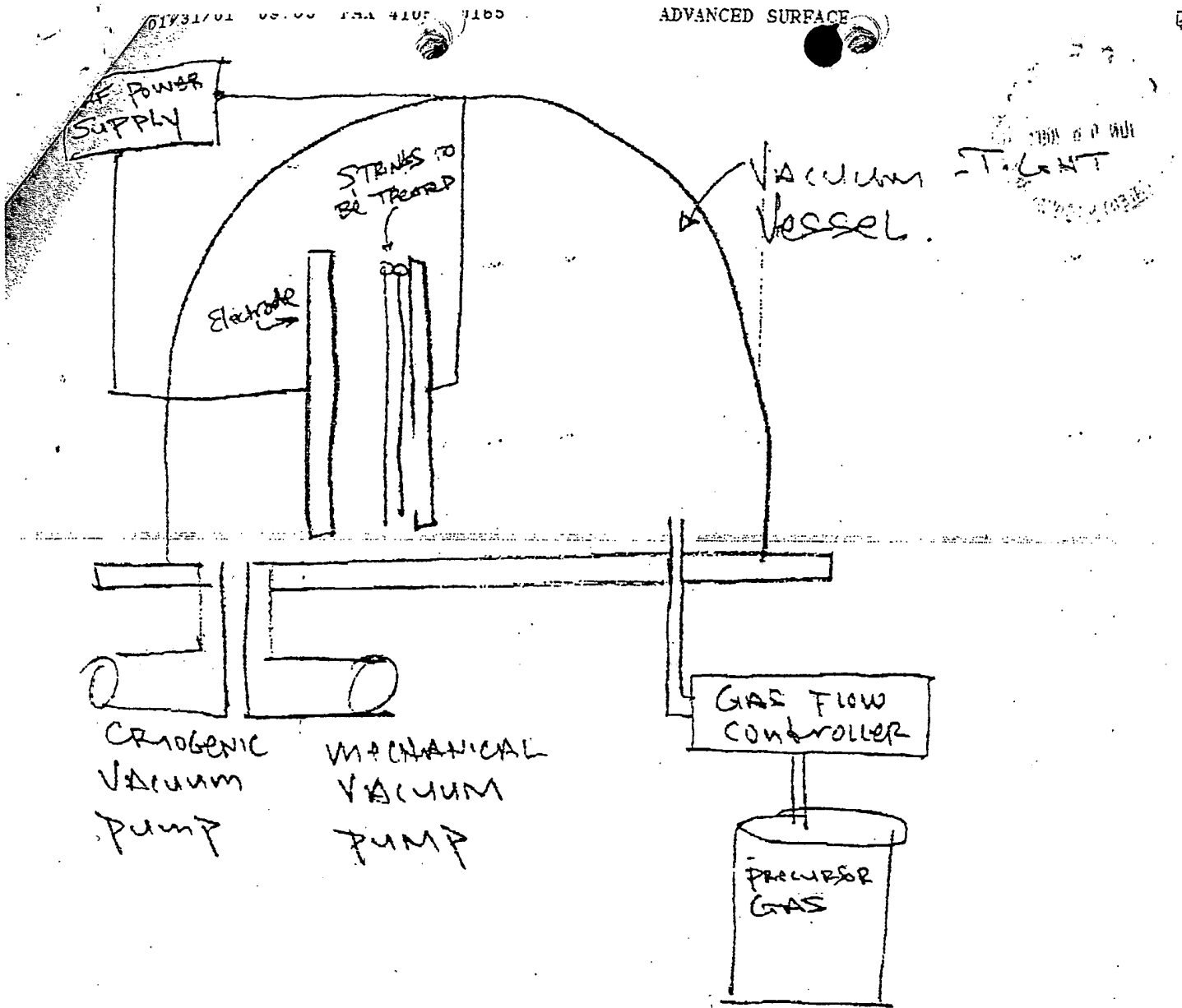
ION BEAM SPATTERING

FIG. 2



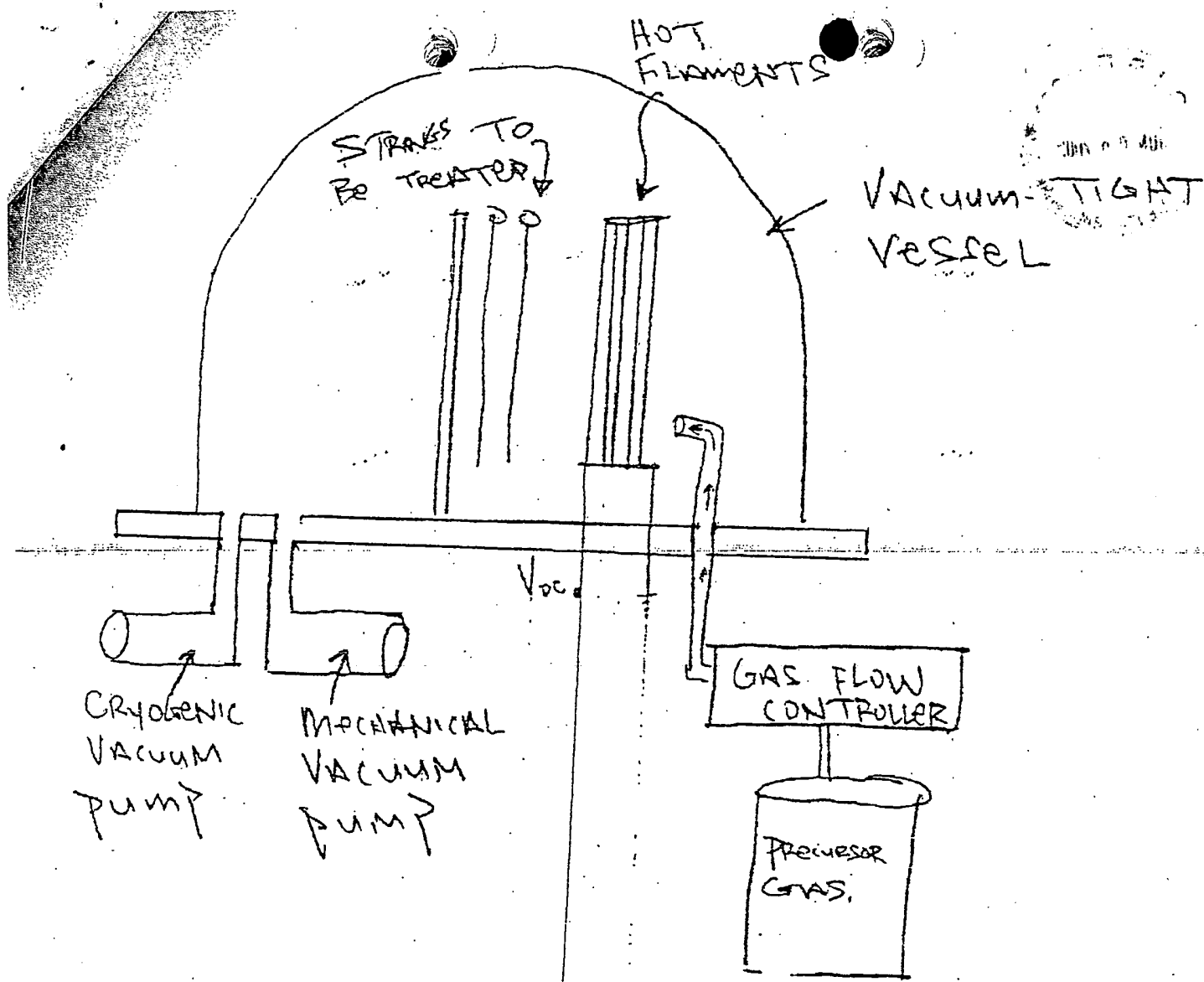
LASER DEPOSITION

FIG 3



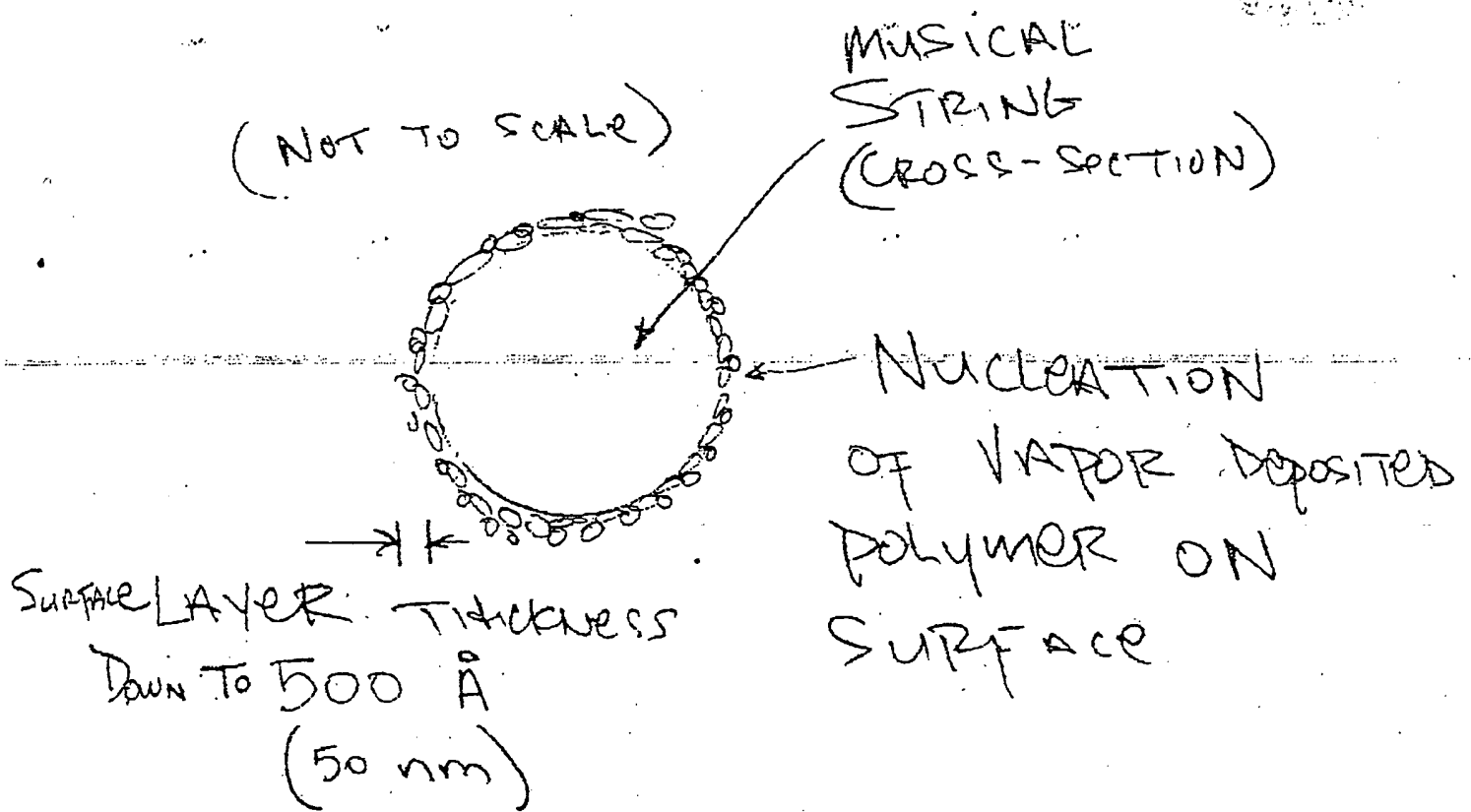
PLASMA CHEMICAL VAPOR DEPOSITION

FIG. 4



HOT FILAMENT CHEMICAL VAPOR DEPOSITION

Fig 5



MUSICAL INSTRUMENT STRING TREATED
W/ VAPOR DEPOSITED POLYMER
NUCLEATE

FIG 6

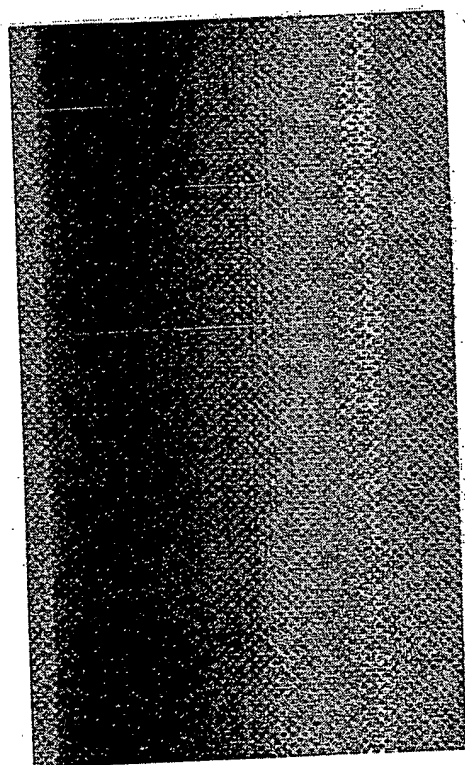
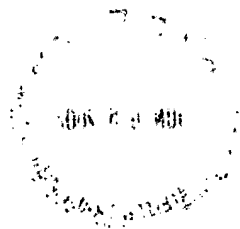


FIG 7

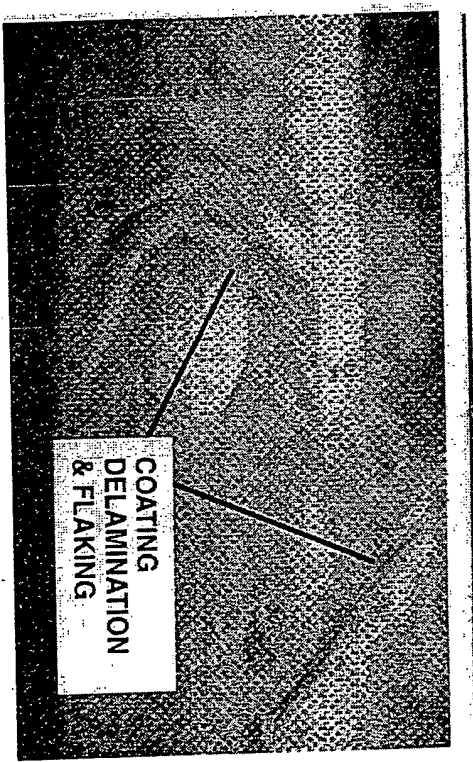
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Fig 8



FIG 9



Substitute drawings (9)

